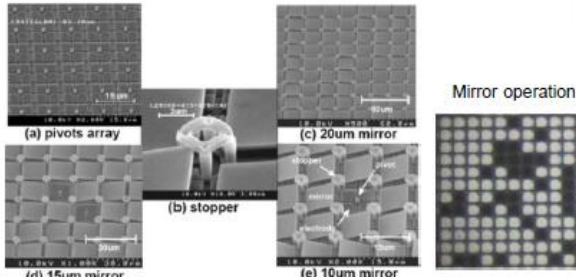
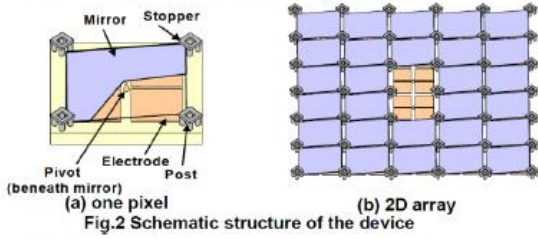
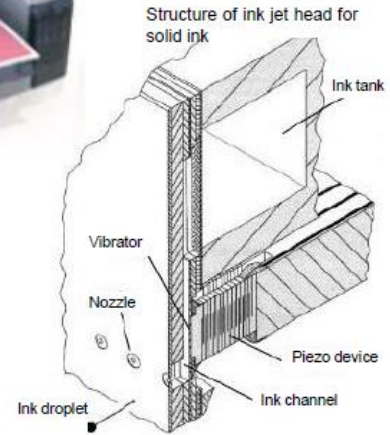


MEMS Activities of RICOH

■ Two dimensional MEMS mirror array device

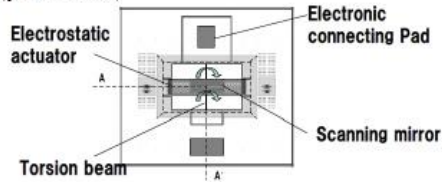


■ Ink jet head for industrial application

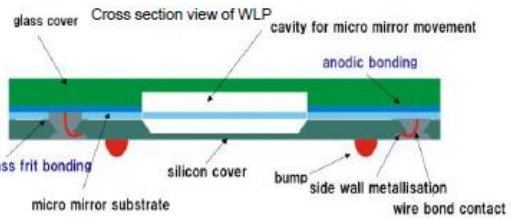
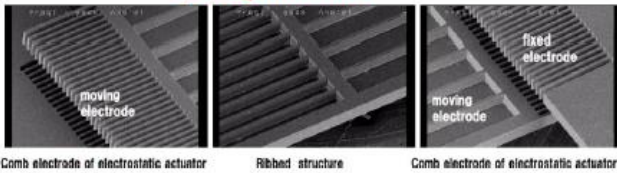


■ WLP (Wafer level package) micro scanner
(Collaborative work with Fraunhofer ENAS)

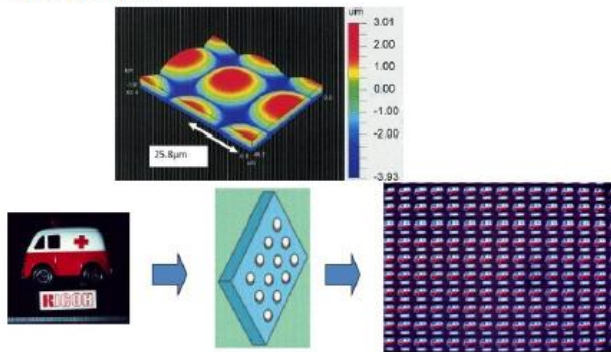
(plane view)



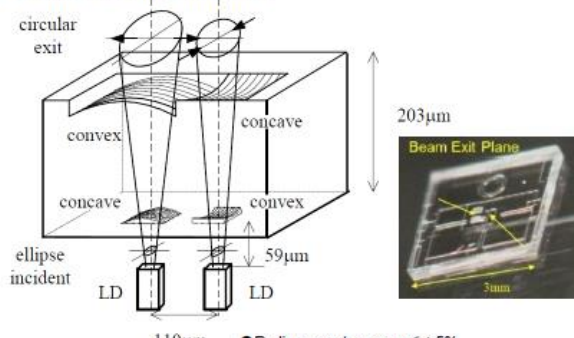
(section view)



■ Micro-lens array



■ Micro-lens multi-beam shaper



■ Laser diode unit with Si two reflection micro mirror

